	Application No.	Applicant(s)
Notice of Allowability	09/818,666 Examiner	FULFORD ET AL. Art Unit
nouse of fine training	Laminer	
	Binh X Tran	1765
The MAILING DATE of this communication appeal All claims being allowable, PROSECUTION ON THE MERITS IS herewith (or previously mailed), a Notice of Allowance (PTOL-85 NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT R	(OR REMAINS) CLOSED in or other appropriate comminities. This application is s	n this application. If not included unication will be mailed in due course. <b>THIS</b>
1. This communication is responsive to <u>01-14-2004</u> .		
2. The allowed claim(s) is/are 1-32,41 and 42.		
3. The drawings filed on 27 March 2001 are accepted by the Examiner.		
4.		
Attachment(s)  1. Notice of References Cited (PTO-892)  2. Notice of Draftperson's Patent Drawing Review (PTO-948)  3. Information Disclosure Statements (PTO-1449 or PTO/SBAPAPER No./Mail Date  4. Examiner's Comment Regarding Requirement for Deposit of Biological Material	6. Interview S Paper No. 7. Examiner's 8. Examiner's 9. Other	NADINE G. NORTON
		SUPERVISORY PATENT EXAMINER

Application/Control Number: 09/818,666 Page 2

Art Unit: 1765

## **EXAMINER'S AMENDMENT**

1. An examiner's amendment to the record appears below. Should the changes and/or additions be unacceptable to applicant, an amendment may be filed as provided by 37 CFR 1.312. To ensure consideration of such an amendment, it MUST be submitted no later than the payment of the issue fee.

- 2. Authorization for this examiner's amendment was given in a telephone interview with Ruben S. Bains on 02-02-2004.
- 3. The application has been amended as follows:

In the claims

Please cancel claims 33-40 as drawn to the non-elected invention.

## Allowable Subject Matter

- 5. Claims 1-32, 41-42 are allowed.
- 6. The following is an examiner's statement of reasons for allowance: Respect to claims 1-12, the reasons for allowance has been discussed in previous office action. Respect to claims 13-32, , 41-42, the cited prior arts fail to suggest or discloses the step of measuring the depth of the etch at two different locations and using the depths to vary the temperature in the subsequently processed semiconducting substrate in conjunction with all other limitations in the claims. The closest prior art (Bukhman et al.) teaches to measure an initial thickness of the wafer before any etching step and a subsequent thickness of the wafer after the etching step.

Application/Control Number: 09/818,666 Page 3

Art Unit: 1765

7. Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance."

## Conclusion

8. Any inquiry concerning this communication or earlier communications from the examiner should be directed to Binh X Tran whose telephone number is (571) 272-1469. The examiner can normally be reached on Monday-Thursday and every other Friday.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Nadine G Norton can be reached on (571) 272-1465. The fax phone number for the organization where this application or proceeding is assigned is 703-872-9306.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

Binh X. Tran

NADINE G. NORTON
SUPERVISORY TAMINER